



## ISC Audits & Reviews SC Summary (December 12, 2019)

Doc.	Title	Result
5842D;	New Standard: Test Method for Metal-Wrap-Through Solar Cell Via Resistance;	Passed
6018;	New Standard: Specification for Silicon Substrates used in fabrication of MEMS Devices;	Passed
6070E;	New Standard: Guide for Identifying Cell Defects In Crystalline Silicon PV Modules By Electroluminescence (EL) Imaging;	Passed
6191;	New Standard: Guide for the Design of Testing and Sorting Equipment for Crystalline Silicon Solar Cells;	Passed
6195A;	Revision to SEMI F104-0312: Particle Test Method for Evaluation of Components Used in Ultrapure Water and Liquid Chemical Distribution Systems, with title change to correct nonconforming title.;	Passed
6290C;	New Standard: Test Method for the Determination of Organic Contaminants Present on Wetted Surfaces of Ultra High Purity Chemical Delivery Systems and Components;	Passed
6291C;	New Standard: Test Method for the Determination of Metallic Elements Present on Wetted Surfaces of Ultra High Purity Chemical Delivery Systems and Components;	Passed
6344A;	New Standard: Specification for Protocol Buffers Common Components;	Passed
6373;	New Standard: Test Method For Accelerated Cell Level Testing For Light And Elevated Temperature Induced Degradation (LeTID) Susceptibility Of Solar Cells;	Passed
6433;	New Standard: Test Method for Determining Conductivity of Chemical Mechanical Polish (CMP) Slurries and Related Chemicals;	Passed
6441A;	Revision to add a New Subordinate Standard, Test Method for Determination of Particle Contribution of Gas Delivery System and its Components through Pulsed Testing, to SEMI F70-0611 (Reapproved 0517), Test Method for Determination of Particle Contribution of Gas Delivery System;	Passed
6457;	Revision to SEMI F38-0699 (Reapproved 0611): Test Method for Efficiency Qualification of Point-of-Use Gas Filters;	Passed
6471A-LI1;	SEMI T23 - Improve clarity on carrier objects and identifiers ;	Passed
6471A-LI2;	SEMI T23 - Add a Compliance Statement and Table ;	Passed
6474;	Revision to SEMI M82-0813: Test Method for the Carbon Acceptor Concentration in Semi-Insulating Gallium Arsenide Single Crystals by Infrared Absorption Spectroscopy;	Passed
6477;	Revision to SEMI F112-0613: Test Method for Determination of Moisture Dry Down Characteristics of Surface Mounted and Conventional Gas Delivery Systems by Cavity Ring Down Spectroscopy (CRDS);	Passed
6484-LI1;	Fix a duplicated SECS-II Data Item and a missing PRC Operation Service Message.;	Passed
6490;	Revision to SEMI C93- 0217: Guide for Determining the Quality of Ion Exchange Resin Used in Polish Applications of Ultrapure Water System;	Passed
6492A-LI1;	Address trademark(s) per Regulations Section 16.4.4;	Passed
6493A-LI1;	Address trademark(s) per Regulations Section 16.4.4;	Passed
6543;	Reapproval of SEMI PV42-0314: Test Method for In-Line Measurement of Waviness of PV Silicon Wafers by a Light Sectioning Technique Using Multiple Line Segments;	Passed
6544;	Reapproval of SEMI PV51-0214: Test Method for In-Line Characterization of Photovoltaic Silicon Wafers by Using Photoluminescence;	Passed



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6545;	Reapproval of SEMI PV52-0214: Test Method for In-Line Characterization of Photovoltaic Silicon Wafers Regarding Grain Size;	Passed
6546;	Revision to SEMI M83-0913 Test Method For Determination Of Dislocation Etch Pit Density In Monocrystals Of III-V Compound Semiconductors;	Passed
6548-LI1;	Add the description of the way to get recipe body which includes ProcessLink ;	Passed
6549-LI1;	Expand and/or add return values to services and events in order to report the type of error, and add new transactions which get the result of recipe validation and are independent from PJ. ;	Passed
6555;	Reapproval of SEMI 3D9-0914: Guide for Describing Materials Properties for a 300 mm 3DS-IC Wafer Stack ;	Passed
6556;	Reapproval of SEMI 3D10-0814: Guide to Describing Materials Properties for Intermediate Wafers for Use in a 300 mm 3DS-IC Wafer Stack;	Passed
6557;	Reapproval of SEMI 3D11-1214: Terminology for Through Glass Via and Blind Via in Glass Geometrical Metrology;	Passed
6559;	Reapproval to SEMI C18-0714: Specification for Acetic Acid;	Passed
6560;	Reapproval to SEMI C23-0714: Specification for Buffered Oxide Etchants;	Passed
6562-LI1;	SEMI E54.23 - Delete "Field Network" from end of title and correct the trademark marking ;	Passed
6562-LI2;	SEMI E54.23 - Change referenced protocol standard to include both "Field Network" and "TSN" variants of CC-Link IE. ;	Passed
6562-LI3;	SEMI E54.23 - Add time synchronization services. ;	Passed
6563;	Reapproval for SEMI E54.18-0914: Specification for Sensor/Actuator Network Specific Device Model for Vacuum Pump Device;	Passed
6564;	Reapproval for SEMI E54.22-0914: Specification for Sensor/Actuator Network Specific Device Model for Vacuum Prepressure Gauges;	Passed
6574;	Reapproval of SEMI M58-1109 (Reapproved 0614)E: Test Method For Evaluating DMA Based Particle Deposition Systems and Processes ;	Passed
R6348B;	Ratification Ballot - Revision to SEMI E30-0418: Specification for the Generic Model for Communications and Control of Manufacturing Equipment (GEM);	Passed
SEMI E54.23-0719	Specification For Sensor/Actuator Network Communications For CC-LINK™ IE Field Network (editorial changes approved by TC Chapter outside of balloting process)	Passed
SEMI T23-0119	Specification For Single Device Traceability For The Supply Chain (editorial changes approved by TC Chapter outside of balloting process)	Passed
SEMI E177-0919	Specification for Transmission Electron Microscope (TEM) Lamella Carriers Used in Electron Microscopy Workflows (editorial changes approved by TC Chapter outside of balloting process)	Passed

Line Item (LI)

For more information, please contact the SEMI Standards Engineer/Coordinator.  
(<http://www.semi.org/standards/contacts>) nearest you.

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Dec 12, 2019